

## ISSM2020 Program Schedule At-A-Glance

December 15 (Day-1)		December 16 (Day-2)	
RoomA	RoomB	RoomA	RoomB
8:50 Opening Remarks, Conference Outline, Program Schedule		8:50 <b>Keynote Speech 3</b> Prof. Takayasu Sakurai/The Univ. of Tokyo Session Chair: Hiroyuki Mori, Renesas Electronics	
9:10 <b>Tutorial Speech 1 (in Japanese)</b> Prof. Yasuyuki Shirai / Tohoku University Session Co-chairs: Dr. Ayako Shimazaki, Toshiba Nanoanalysis Dr. Keiji Horioka		9:30 Break(10mins)	
9:50 Break (5mins)		9:40 <b>Keynote Speech 4</b> Dr. Vivek Jain / Maxim Integrated Session Chair: Toshiyuki Uchino, Kokusai Electric	
9:55 <b>Tutorial Speech 2 (in Japanese)</b> Prof. Koji Eriguchi / Kyoto University Session Co-chairs: Dr. Ayako Shimazaki, Toshiba Nanoanalysis Dr. Keiji Horioka		10:20 Break (5mins)	
10:35 Break (10mins)		10:25 <b>Keynote Speech 5</b> Prof. Takeshi ABE / Kyoto Univ. Session Chair: Dr. Shin-ichi Imai, Hitachi High-Tech Solutions	
10:45 <b>Keynote Speech1</b> Masataka Osaki / NVIDIA Japan Session Chair: Dr. Shin-ichi Imai, Hitachi High-Tech Solutions		11:05 Break (5mins)	
11:25 Break (5mins)		11:10 <b>Keynote Speech 6</b> Akira Minamikawa / Omdia Session Chair: Dr. Hiroshi Akahori, KIOXIA Corporation	
11:30 <b>Keynote Speech 2</b> Dr. Nicky Lu / ETRON Session Chair: Shuichi Inoue, ATONARP		11:50 <b>Lunch Break &amp; Exhibitor Presentation</b> 40mins	
12:10 <b>Lunch Break &amp; Exhibitor Presentation</b> 40mins		12:30 <b>AI Contest</b> * SEM Image Classification AI Algorithm Contest * Semiconductor Manufacturing Fab Data AI utilization Idea Contest Session Chair: Dr. Shin-ichi Imai, Hitachi High-Tech Solutions	
12:50 <b>EDTM2020-invited</b> Session Chair: Dr. Ayako Shimazaki, Toshiba Nanoanalysis		13:30 Break (10mins)	
13:10 Break (10mins)		13:40 <b>Keynote Speech 7</b> Dr. Salvatore Coffa / ST Microelectronics Session Chair: Yasutoshi Okuno, SCREEN Semiconductor Solutions	
13:20 <b>Session A-1:</b> Process/Material Optimization (PO)-1 Session Co-chairs: Dr. Tsuyoshi Moriya, Tokyo Electron Dr. Shin-ichi Imai, Hitachi High-Tech Solutions		14:20 Break (10mins)	
13:40 <b>Session B-1:</b> Worker and WIP Control (WC) & Manufacturing Strategy (MS) Session Co-chairs: Katsutoshi Ozawa, OMRON Takatoshi Yasui, Tower Partners Semiconductor		14:30 <b>Session A-4:</b> Process Monitoring & Control Method (PM)-3 Session Co-chairs: Yuji Yamada, KIOXIA Dr. Kazuhito Matsukawa, SUMCO	
14:00 Author's interview by Paper & Break		14:50 <b>Session B-4:</b> Yield & Defect Control (YD)-2 Session Co-chairs: Takahiro Tsuchiya, United Semiconductor Japan Shinsuke Mizuno, Applied Materials Japan	
14:20 <b>Session A-2:</b> Process/Material Optimization (PO)-2 & Process Monitoring & Control Method (PM)-1 Session Co-chairs: Hiroyuki Inoue, Texas Instruments Japan Masahiro Shimbo, ON Semiconductor		15:10 Author's interview by Paper & Break	
14:40 <b>Session B-2:</b> Intelligent Data Management (ID)-1 & Material Informatics (MI) & New Gas, New Liquid, and New Resist Technologies (NM) Session Co-chairs: Kazuki Yokota, Renesas Electronics Dr. Kenji Watanabe, SanDisk		16:10 <b>Session A-5:</b> Process Monitoring & Control Method (PM)-4 & Intelligent Data Management (ID)-2 Session Co-chairs: Masami Aoki, KLA-Tencor Japan Hiroyuki Inoue, Texas Instruments Japan	
15:00 Author's interview by Paper & Break		16:30 <b>Session B-5:</b> Final Manufacturing & Integrated Package (FM) Session Co-chairs: Kazunori Kato, Advanced Interface Technology Dr. Kenji Miyake, PMT	
15:20 Author's interview by Paper & Break		16:50 Author's interview by Paper & Break	
15:40 Author's interview by Paper & Break		17:10 Author's interview by Paper & Break	
16:00 Author's interview by Paper & Break		17:30 Author's interview by Paper & Break	
16:20 <b>Session A-3:</b> Process Monitoring & Control Method (PM)-2 & Ultraclean Technology (UT) Session Co-chairs: Isamu Namose, OMRON Takayuki Hisamatsu, Sony Semiconductor Manufacturing		17:50 <b>Award &amp; Networking</b>	
16:40 <b>Session B-3:</b> Yield & Defect Control (YD)-1 Session Co-chairs: Masami Aoki, KLA-Tencor Japan Akimasa Soyano, JSR			
17:00 Author's interview by Paper & Break			
17:20 Author's interview by Paper & Break			
17:40 Author's interview by Paper & Break			
18:00 Break (10mins)			
18:10 Networking			
19:00		19:00	

ISSM AI Contest  
Semiconductor  
Manufacturing  
Fab Data  
AI utilization  
Idea Contest  
  
VIDEO & Voting

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Semiconductor  
Manufacturing  
Fab Data  
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VIDEO